

PROCEEDINGS OF SPIE

AOPC 2023: Optical Design and Manufacturing

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Editors

**25–27 July 2023
Beijing, China**

Sponsored by
Chinese Society for Optical Engineering (CSOE) (China)

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Published by
SPIE

Volume 12964

Proceedings of SPIE 0277-786X, V. 12964

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

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Author(s), "Title of Paper," in *AOPC 2023: Optical Design and Manufacturing*, edited by Lingbao Kong, Dawei Zhang, Xichun Luo, Proc. of SPIE 12964, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510672345
ISBN: 9781510672352 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)
SPIE.org

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